

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Liu

Application No.: 10/634,964

Filed: 8/5/2003

Title: CHEMICAL MECHANICAL
PLANARIZATION COMPOSITIONS FOR
REDUCING EROSION IN SEMICONDUCTOR
WAFERS

Attorney Docket No.: 02039US

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Art Unit:

1765

Examiner:

Patricia A. George

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CENTRAL FAX CENTER**FEB 10 2006**RESPONSE

Dear Sir:

In response to the Office Action of November 18, 2005, having a statutory due date of February 18, 2006, please reconsider the earlier-amended application.